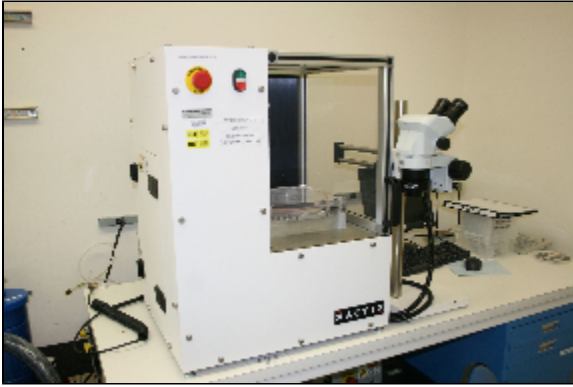


Xactic Etcher



Facts

The Xactic Etcher is a non-plasma dry etch tool.

- It employs XeF_2 to bulk etch exposed silicon surfaces.
- It is intended as a release etch for silicon in MEMs applications
- It is *not* intended as a deep silicon etcher or a through-hole etcher, and is completely isotropic

Personnel

- Tool Engineer - [John Nash](#)
- Process Engineer - [Sean O'Brien](#)
- Process Engineer - [Patricia Meller](#)

Tool & Process Information

- [Dry Etch Process Information](#)

Manuals & Users

- [Xactic Etcher Manual](#)
- [Xactic Etcher Certification Checklist](#)